Characterization Facilities:

1. Electrical characterization set ups for I-V, C-V, low frequency noise measurements as a function of temperature (LN2 to 200 degree Celsius), DC probe station

2. Multimode scanning probe microscope (SPM) with various modes available such as AFM, MFM,KPFM,STM and CAFM.

3. X-ray diffractrometer for thin film samples,Tabletop SEM with EDX.

4. Micro-Raman and Photoluminescence measurement set up with LHe cryostat.

5. Fourier transform infrared spectroscopy (FTIR), UV-vis-NIR spectrophotometer .

6. Variable angle spectroscope ellipsometry, Stylus profilometer, Optical profilometer, Stress measurement system.

7. Gas chromatography mass spectrometry (GCMS).

photoelectrochemical (PEC) Workstation, Dynamic light scattering (DLS) system